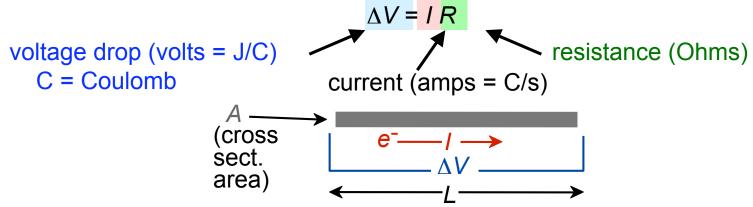
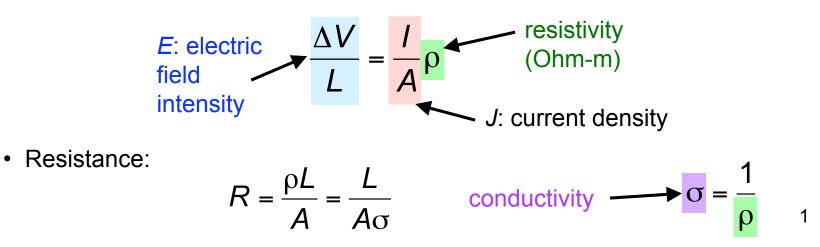
Electrical conductivity

• Ohm's Law:



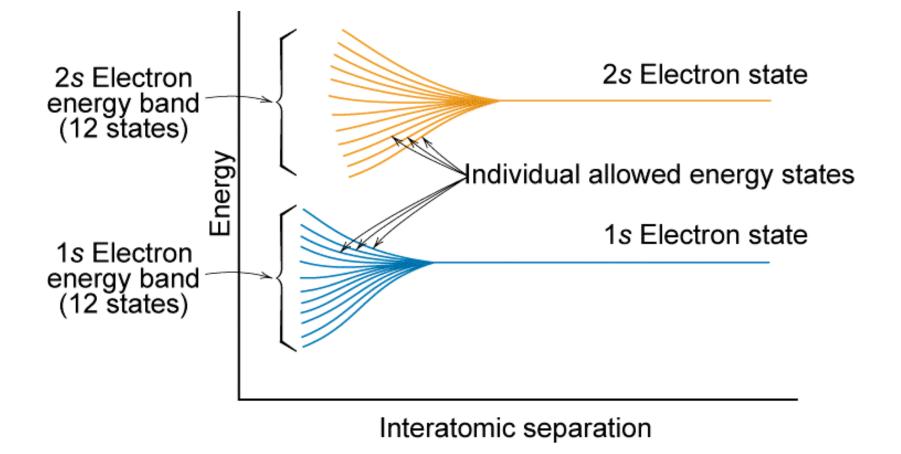
- Resistivity, ρ and Conductivity, σ:
 - -- geometry-independent forms of Ohm's Law
 - -- Resistivity is a material property & is independent of sample



Conductivity: comparison

• Room T values (Ohm-m) ⁻¹ = (Ω - m) ⁻¹				
METALS Silver Copper Iron	conductors 6.8 x 10 ⁷ 6.0 x 10 ⁷ 1.0 x 10 ⁷	CERAMICS Soda-lime glass Concrete Aluminum oxide	10 ⁻¹⁰ -10 ⁻¹¹ 10 ⁻⁹ <10 ⁻¹³	
SEMICONDU Silicon Germanium GaAs	JCTORS 4 x 10 ⁻⁴ 2 x 10 ⁰ 10 ⁻⁶	POLYMERS Polystyrene Polyethylene	<10 ⁻¹⁴ 10 ⁻¹⁵ -10 ⁻¹⁷	
	emiconductors bles 18.1, 18.3, and 18.4, Calli	ster 7e.	insulators	

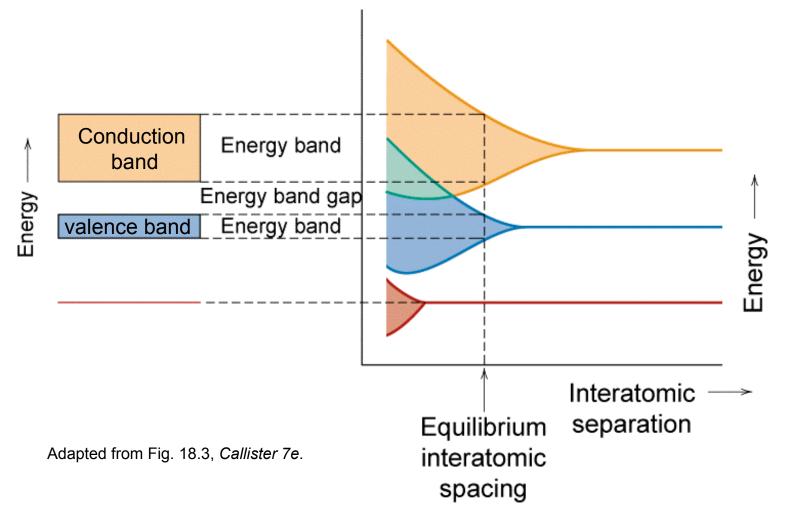
Electronic band structure



Adapted from Fig. 18.2, Callister 7e.

Electronic band structure

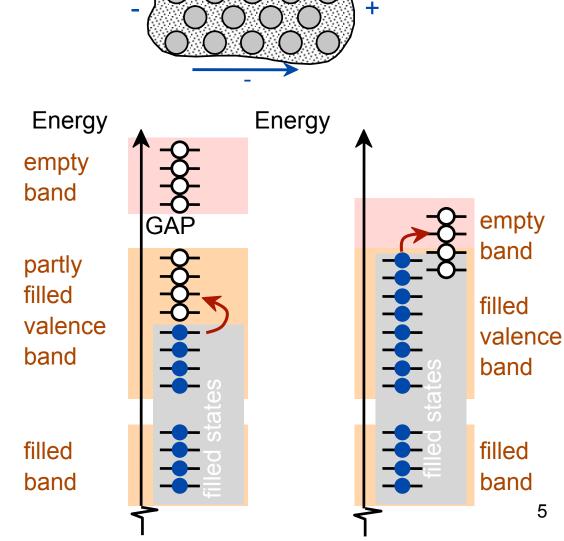
Valence band – filled – highest occupied energy levels
Conduction band – empty – lowest unoccupied energy levels



4

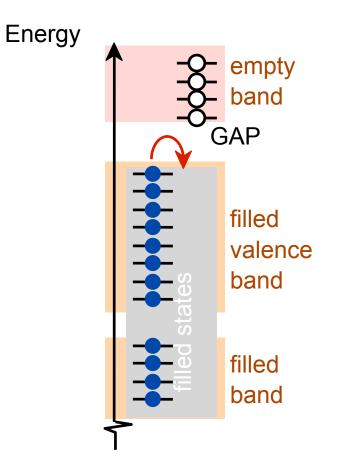
Conduction and electron transport

- Metals (Conductors):
- -- Thermal energy puts many electrons into a higher energy state.
- Energy States:
- -- for metals nearby energy states are accessible by thermal fluctuations.

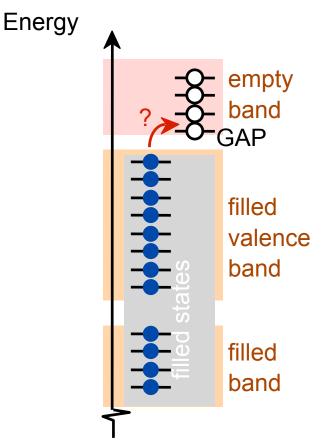


Energy states: Insulators & semiconductors

- Insulators:
 - -- Higher energy states not accessible due to gap (> 2 eV).

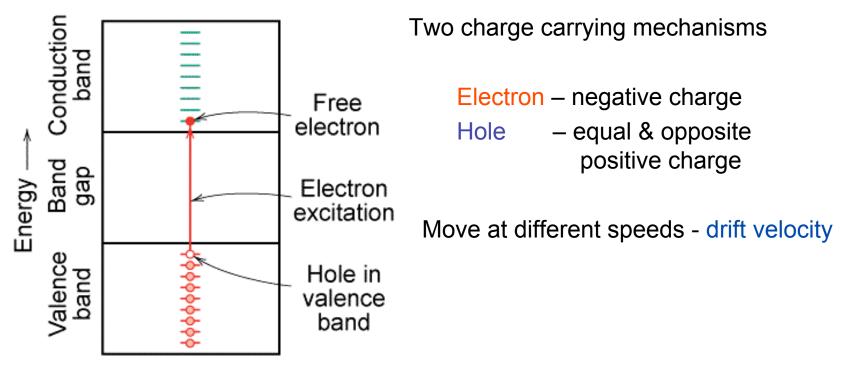


- Semiconductors:
 - -- Higher energy states separated by smaller gap (< 2 eV).



Charge carriers

Adapted from Fig. 18.6 (b), *Callister 7e*.



Higher temp. promotes more electrons into the conduction band

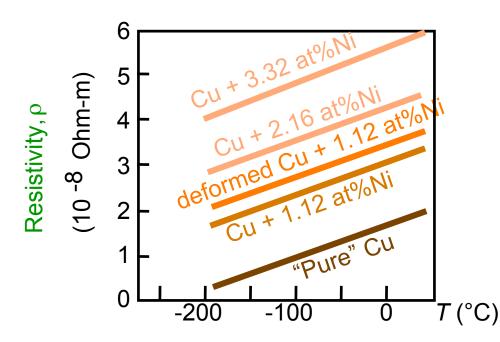
•	σ ↑ as	7个
• •		, , ,

Electrons scattered by impurities, grain boundaries, etc.

Charge carriers

- Imperfections increase resistivity
 - -- grain boundaries
 - -- dislocations
 - -- impurity atoms
 - -- vacancies

These act to scatter electrons so that they take a less direct path.

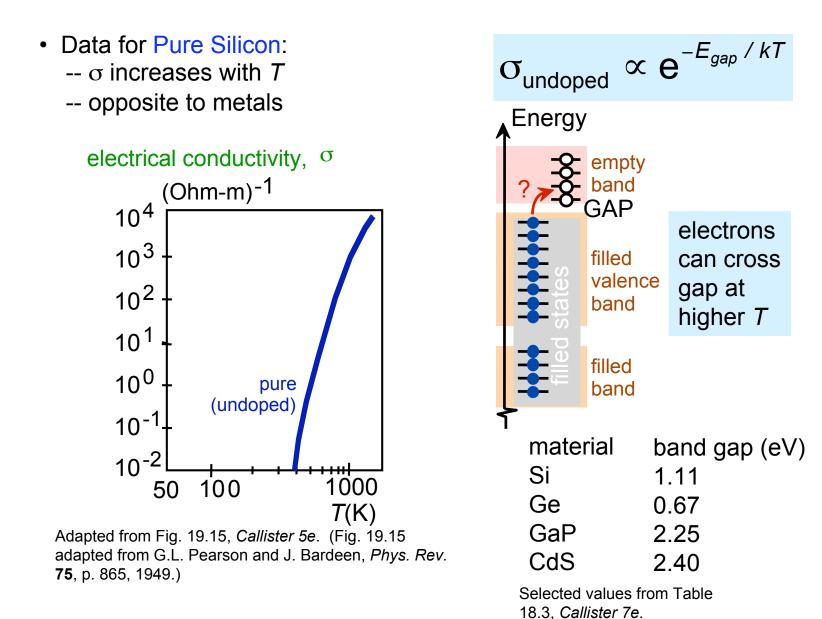


Adapted from Fig. 18.8, *Callister 7e*. (Fig. 18.8 adapted from J.O. Linde, *Ann. Physik* **5**, p. 219 (1932); and C.A. Wert and R.M. Thomson, *Physics of Solids*, 2nd ed., McGraw-Hill Book Company, New York, 1970.)

- Resistivity
 increases with:
 - -- temperature
 - -- wt% impurity
 - -- %CW

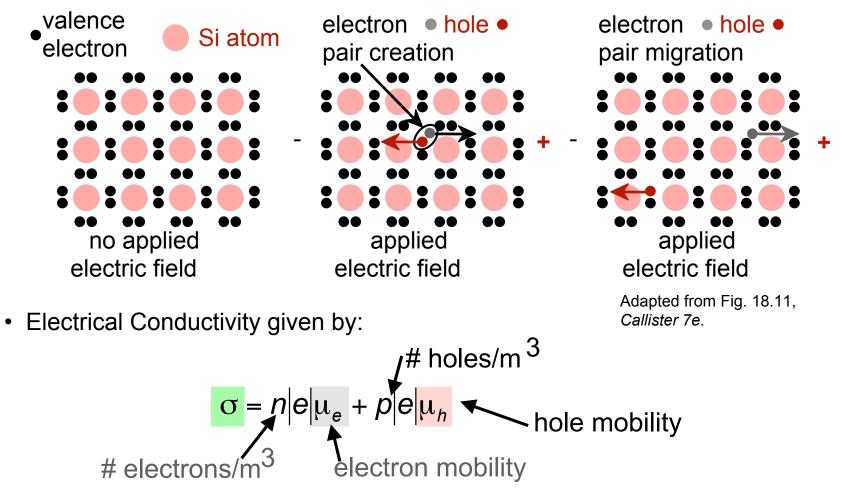


Pure semiconductors: Conductivity vs T



Conduction in terms of electron and hole migration

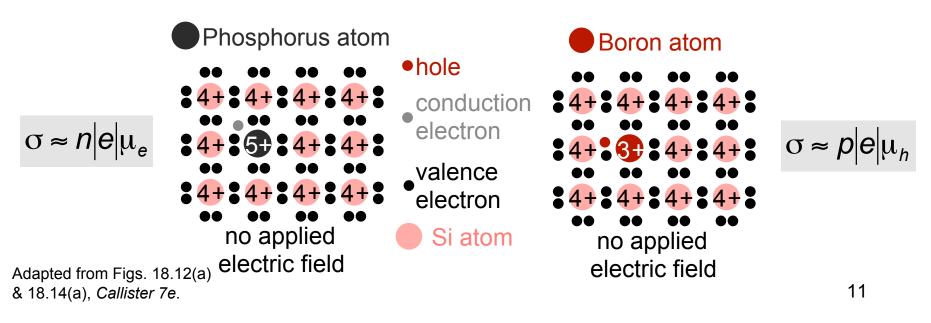
Concept of electrons and holes:



Intrinsic vs extrinsic conduction

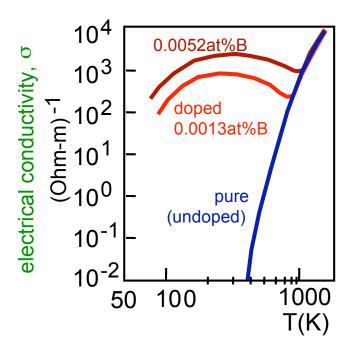
- Intrinsic:
 - # electrons = # holes (n = p)
 - --case for pure Si
- Extrinsic:
 - $--n \neq p$
 - --occurs when impurities are added with a different # valence electrons than the host (e.g., Si atoms)
- *n*-type Extrinsic: (*n* >> *p*)

p-type Extrinsic: (*p* >> *n*)



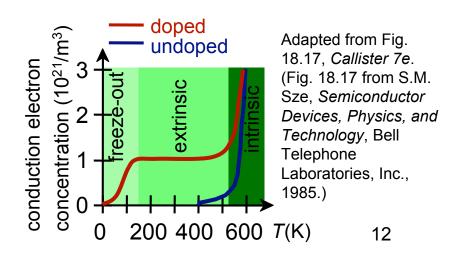
Doped semiconductor: conductivity vs. T

- Data for Doped Silicon:
 -- σ increases with doping
 - -- reason: imperfection sites lower the activation energy to produce mobile electrons.



Adapted from Fig. 19.15, *Callister 5e*. (Fig. 19.15 adapted from G.L. Pearson and J. Bardeen, *Phys. Rev.* **75**, p. 865, 1949.)

- Comparison: intrinsic vs extrinsic conduction...
 - -- extrinsic doping level: 10²¹/m³ of a *n*-type donor impurity (such as P).
 - for *T* < 100 K: "freeze-out", thermal energy insufficient to excite electrons.
 - -- for 150 K < *T* < 450 K: "extrinsic"
 - -- for T >> 450 K: "intrinsic"



Doped semiconductor: conductivity vs. T

Intrinsic Conductivity

 $\sigma = n|e|\mu_e + p|e|\mu_e$

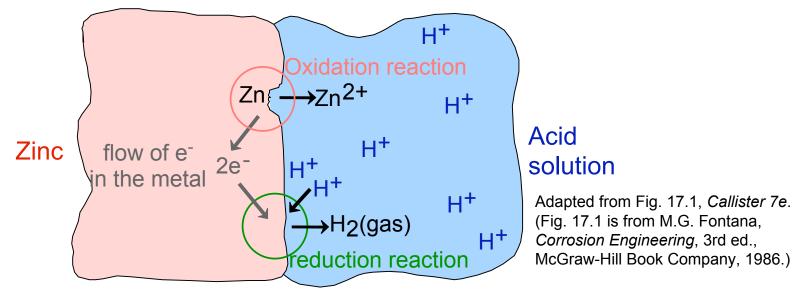
- for intrinsic semiconductor n = p $\therefore \quad \sigma = n|e|(\mu_e + \mu_n)$
- Ex: GaAs

$$n = \frac{\sigma}{\left|e\right|\left(\mu_e + \mu_n\right)} = \frac{10^{-6} (\Omega \cdot m)^{-1}}{(1.6x10^{-19} \text{C})(0.85 + 0.45 \text{ m}^2/\text{V} \cdot \text{s})}$$

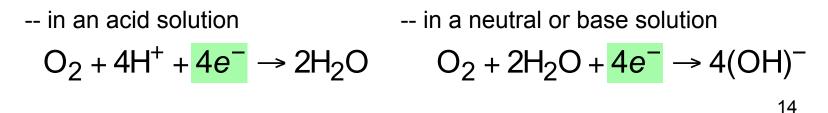
For GaAs $n = 4.8 \times 10^{24} \text{ m}^{-3}$ For Si $n = 1.3 \times 10^{16} \text{ m}^{-3}$

Corrosion of zinc in acid

• Two reactions are necessary: -- oxidation reaction: $Zn \rightarrow Zn^{2+} + 2e^{-}$ -- reduction reaction: $2H^{+} + 2e^{-} \rightarrow H_{2}(gas)$

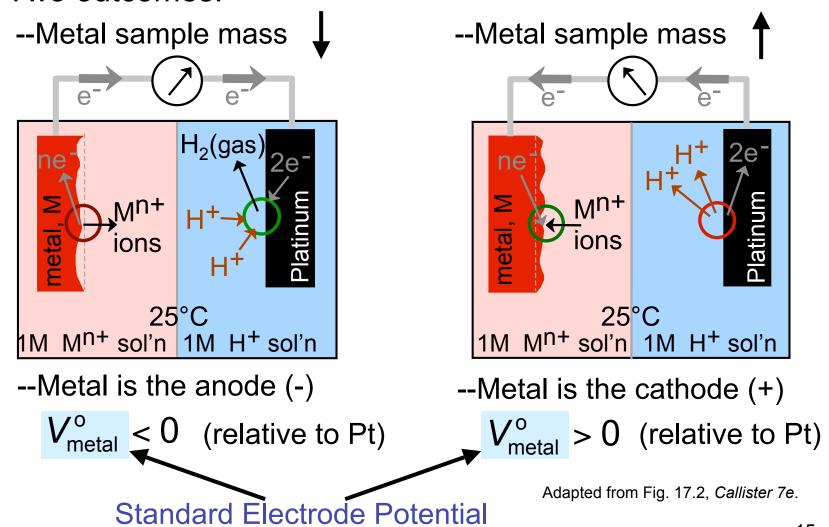


• Other reduction reactions:

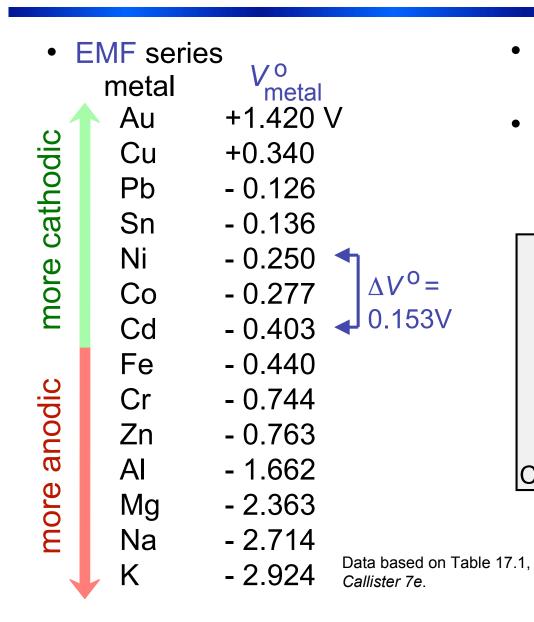


Standard hydrogen (EMF) test

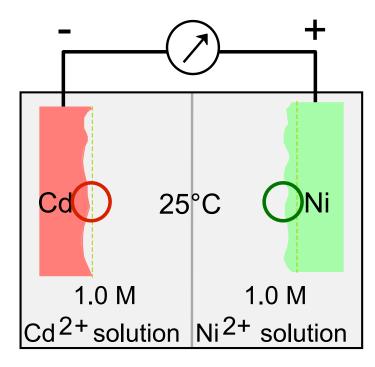
• Two outcomes:



Standard EMF series



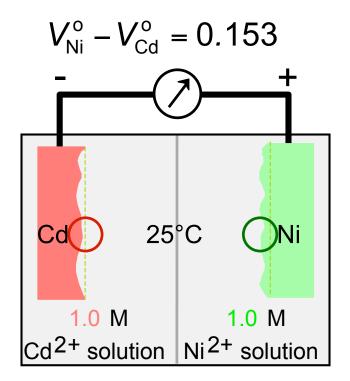
- Metal with smaller
 V^o_{metal} corrodes.
- Ex: Cd-Ni cell

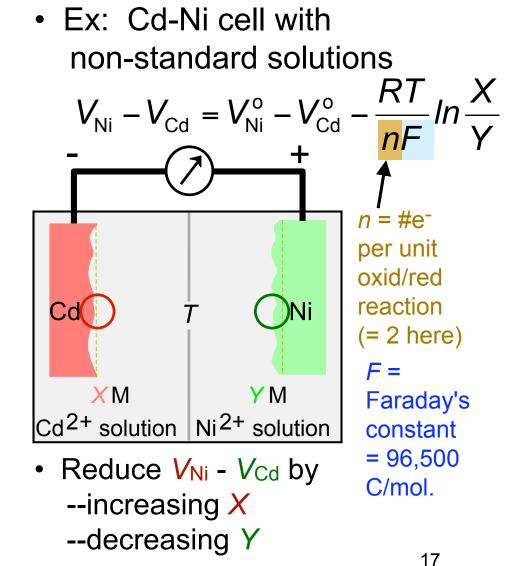


Adapted from Fig. 17.2, *Callister 7e*.

Effect of solution concentration

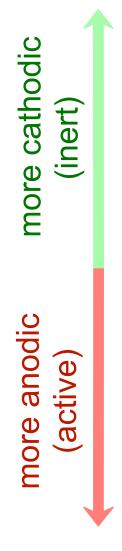
• Ex: Cd-Ni cell with standard 1 M solutions





Galvanic series

• Ranks the reactivity of metals/alloys in seawater



Platinum Gold Graphite Titanium Silver 316 Stainless Steel Nickel (passive) Copper Nickel (active) Tin Lead 316 Stainless Steel Iron/Steel **Aluminum Alloys** Cadmium Zinc Magnesium

Based on Table 17.2, *Callister* 7e. (Source of Table 17.2 is M.G. Fontana, *Corrosion Engineering*, 3rd ed., McGraw-Hill Book Company, 1986.)

Forms of corrosion

- Uniform Attack Oxidation & reduction occur uniformly over surface.
- Selective Leaching Preferred corrosion of one element/constituent (e.g., Zn from brass (Cu-Zn)).
 - Intergranular Corrosion along grain boundaries, often where special phases exist.

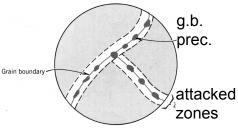
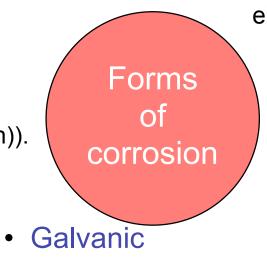


Fig. 17.18, Callister 7e.



Stress & corrosion work together at crack tips.



Dissimilar metals are physically joined. The more anodic one corrodes.(see Table 17.2) Zn & Mg very anodic. • Erosion-corrosion Break down of passivating layer by erosion (pipe elbows).

• Pitting

Downward propagation of small pits & holes.

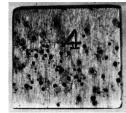


Fig. 17.17, *Callister 7e*. (Fig. 17.17 from M.G. Fontana, *Corrosion Engineering*, 3rd ed., McGraw-Hill Book Company, 1986.)

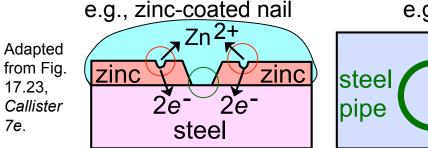
• Crevice Between two pieces of the same metal.



Fig. 17.15, *Callister 7e*. (Fig. 17.15 is courtesy LaQue Center for Corrosion Technology, Inc.) 19

Controlling corrosion

- Metal oxide Self-protecting metals! Metal (e.g., Al, -- Metal ions combine with O to form a thin, adhering oxide layer that slows corrosion. stainless steel)
- Reduce T (slows kinetics of oxidation and reduction)
- Add inhibitors
 - -- Slow oxidation/reduction reactions by removing reactants (e.g., remove O₂ gas by reacting it w/an inhibitor).
 - -- Slow oxidation reaction by attaching species to the surface (e.g., paint it!).
- Cathodic (or sacrificial) protection
 - -- Attach a more anodic material to the one to be protected.



e.g., Mg Anode

e⁻

aho

20

Adapted from Fig. 17.22(a), Cu wire Callister 7e. (Fig. 17.22(a) is from M.G. Fontana, Corrosion Mg Mg² Engineering, 3rd ed., McGraw-Hill Book Co., 1986.)